

EV550719147



Investor: Brian E. Cron

Title: **Methods for Conditioning Surfaces of Polishing Pads After Chemical Mechanical Polishing**

Assignee: **Micron Technology, Inc.**

Serial No.: **10/075,172**

Filed: **February 13, 2002 [RCE Filed Herewith]**

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. No admission is made regarding whether the listed reference is prior art.

Citation of this patent is respectfully requested.

Dated:

7/27/05

By:

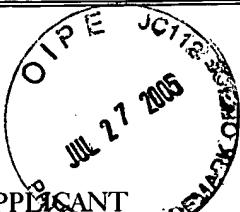
Respectfully submitted,

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Sheet 1 of 1

'Form PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICELIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)ATTY. DOCKET NO.  
MI22-1804SERIAL NO.  
10/075,172APPLICANT  
Brian E. CronFILING DATE  
Feb. 13, 2002 [RCE filed herewith]GROUP  
3723

## U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,776,691 B2	08/04	Nishimura et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-class	Translation	
							Yes	No
	AK							
	AL							
	AM							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AN	
	AO	
	AP	
EXAMINER	DATE CONSIDERED	

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.